

Serial No. 09/935,352

PATENT
Docket No. 58027-011900

Claim 75 (new): The method for aperturing a VCSEL according to claim 35, further comprising etching at least one of the first and the second cladding surface with a reactive ion etch.

Claim 76 (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 55, wherein the at least one material includes Al.

Claim 77 (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 55, wherein the at least one material includes Ga.

Claim 78 (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 1, wherein the first and the second cladding surfaces are made of InP.

Claim 79 (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 1, wherein the aperture layer is an active region.

Claim 80 (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 4, wherein the aperture layer is an active region.

Claim 81 (new): The vertical-cavity surface-emitting laser (VCSEL) according to claim 10, wherein the aperture layer is an active region.

Claim 82 (new): The vertical-cavity surface-emitting laser (VCSEL) according to claim 10, wherein the aperture layer is comprised of InAlGaAs.

Claim 83 (new): The vertical-cavity surface-emitting laser (VCSEL) according to claim 10, wherein the first and the second cladding surfaces are made of InP.

Claim 84 (new): The vertical-cavity surface-emitting laser (VCSEL) according to claim 22, wherein the aperture layer is comprised of InAlGaAs.

Claim 85 (new): The vertical-cavity surface-emitting laser (VCSEL) according to claim 22, wherein the aperture layer is an active region.

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Claim ~~88~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 35, wherein the first and the second cladding layers are made of InP.

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Claim ~~89~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 35, wherein the aperture layer is an active region.

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Claim ~~90~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 35, wherein the aperture layer is comprised of InAlGaAs.

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Claim ~~91~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 51, wherein the at least one cladding surface is made of InP.

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Claim ~~92~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 51, wherein the aperture layer is comprised of InAlGaAs.

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Claim ~~93~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 51, wherein the aperture layer is an active region.

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Claim ~~94~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 55, wherein the aperture layer is comprised of InAlGaAs.

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Claim ~~95~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 55, wherein the aperture layer is an active region.

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Claim ~~96~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 61, wherein the aperture layer is comprised of InAlGaAs.

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Claim ~~97~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 61, wherein the aperture layer is an active region.

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Claim ~~98~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 61, wherein the cladding surfaces are made of InP.

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Claim ~~99~~ (new): The method for aperturing a VCSEL according to claim 61, wherein the aperture is formed by selectively etching the aperture layer by an etchant composed of citric acid and hydrogen peroxide in a predetermined ratio.

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Claim ~~100~~ (new): The method for aperturing a vertical-cavity surface-emitting laser (VCSEL) according to claim 4, wherein the first and the second cladding surfaces are made of InP.